Silicon Nanowires fabrication and surface nanostructuration by Metal Assisted Chemical Etching

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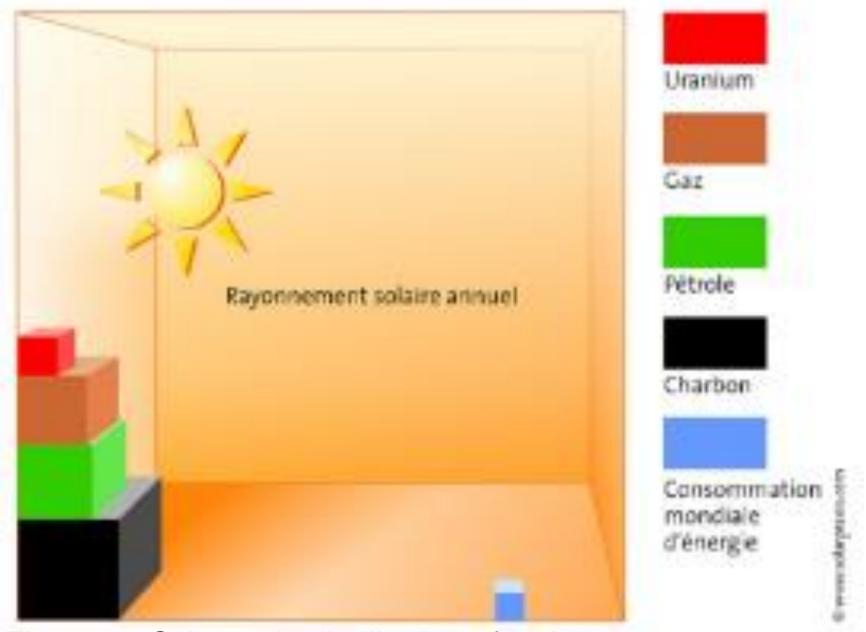


Figure 1 - Schematic distribution of global energy resources. Source: Solarpraxis



Global Mean Solar Irradiance



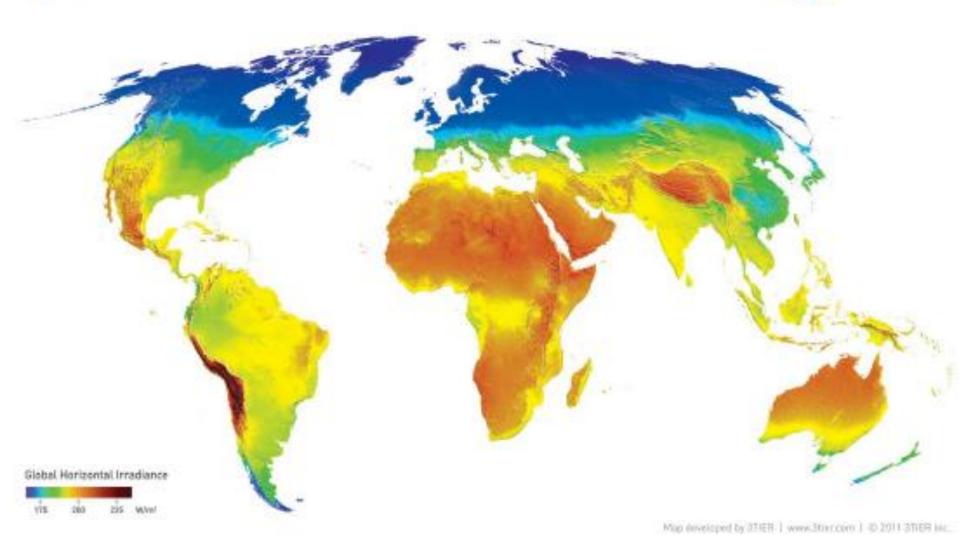


Figure 1.3 - Carte de l'irradiance solaire sur la Terre, d'après 3TIER (http://www.3tier.com/static/ttcms/us/images/support/maps/3tier_solar_irradiance.jpg)

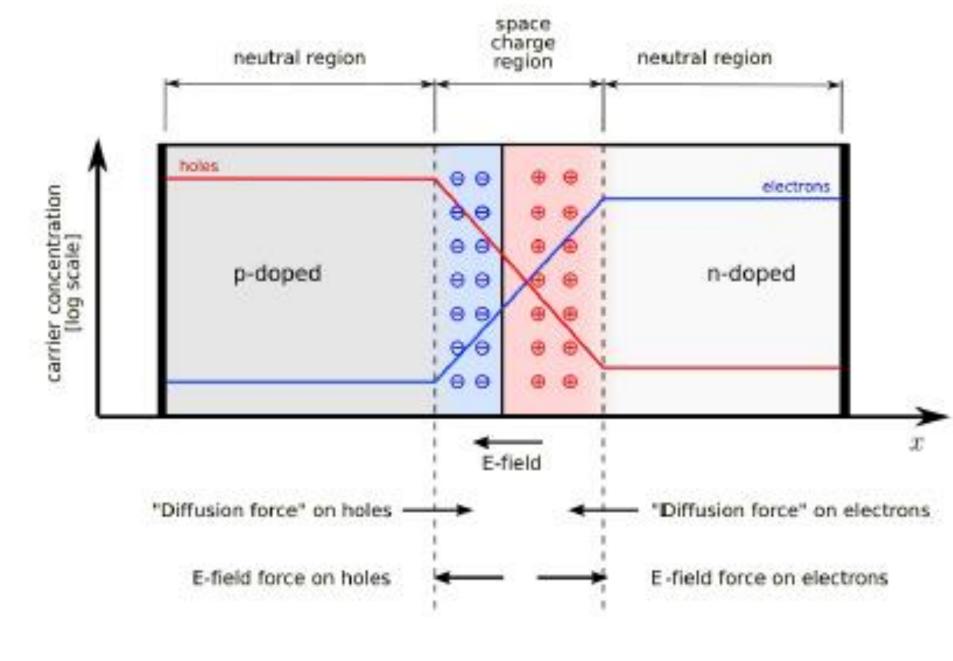


Figure 3 - Schematic of a p-n junction. Source: phD David Cohen

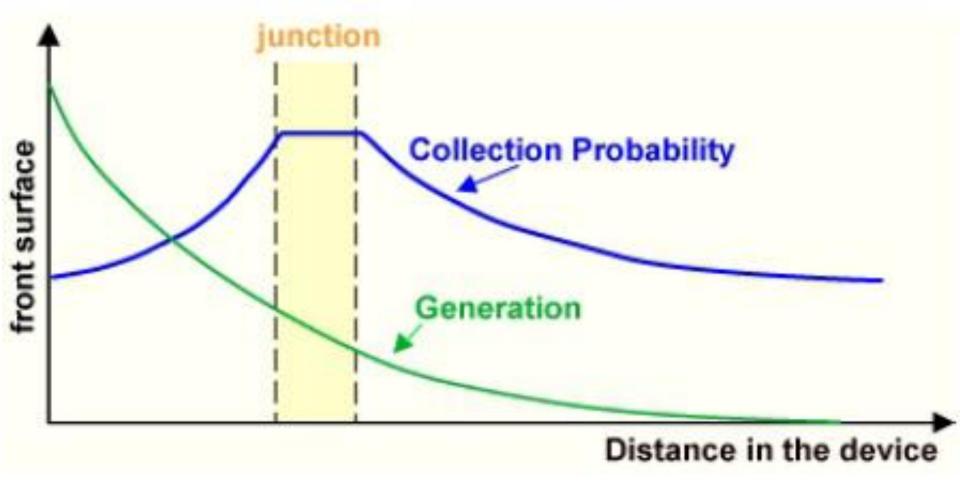


Figure 4 – carriers collection probability versus cell position. Source: phD David Cohen

Three types of recombinaison:

- Radiative recombinaisons: frequently present in direct

GAP material, so negligible in Silicon

AUGER Recombination: This type of recombination involves three carriers.

Traps Assisted Recombination: Also called Shockley-Read-Hall recombination, they are present in materials which contain defects (grain boundaries, impurities, etc.)

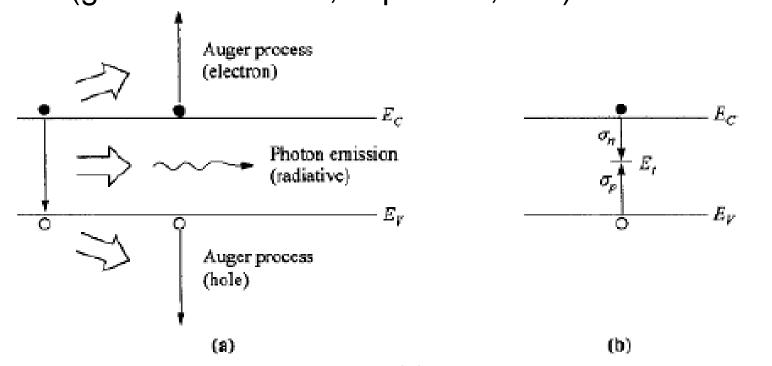


Figure 5 - Mechanisms of recombination. (a) radiative recombination resulting in the emission of a photon and Auger recombination resulting in the increase in energy of an electron or a hole. (b) Trap Assisted Recombination is the capture cross section of the trap. According Sze [1]

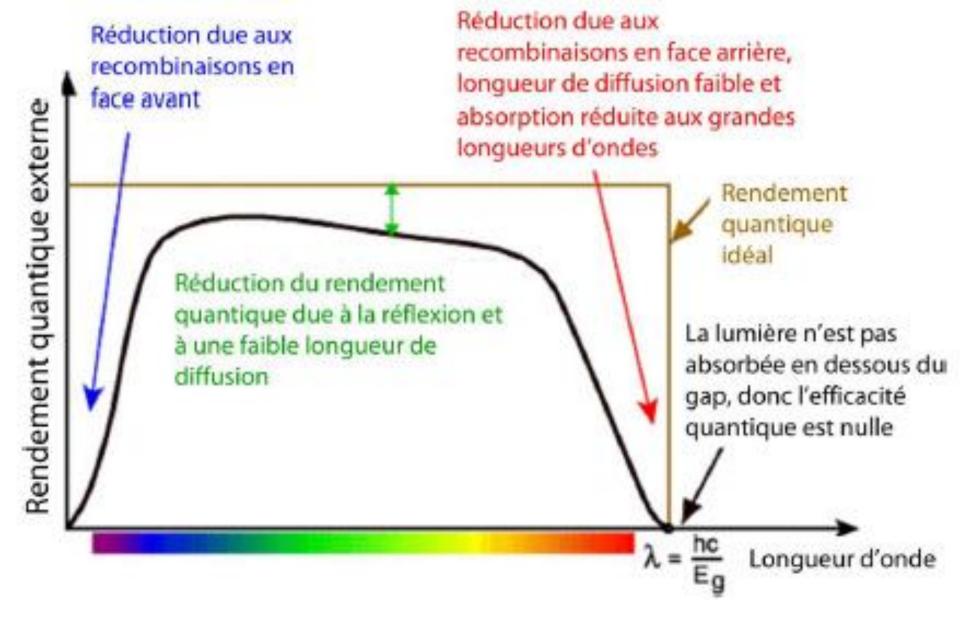


Figure 6 –External quantum efficiency of a solar cell and explanations of the various losses. Source : http://www.pveducation.org/pvcdrom/solar-cell-operation/quantum-efficiency

SOLUTIONS

Definition: What do we say nanostructure? a nanostructure, according to be mono-, bi-or tridimensional, has at least one of its dimensions smaller than 100 nm.

Double interest:

- From a fundamental point of view, small size —— new properties (electronic, magnetic, optical)
- From a technological point of view, nanostructures can increase the integration capacity of electronic components or memories stocking densities...

Outline

- Objective of the Work
- Why Silicon Surface Nanostructuration?
- Silicon Nanowires and Surface
 Nanostructuration Processes by MACE
- Results and Discussion
- Conclusion and Perpectives

Objective of the Work

- Before using these nano-objects in technological applications, it is important to study in order to control their properties from their size, shape, interface, interaction with their environment...
- The starting point of nanoscience and nanotechnology is therefore based on the realization of nano-structures, which are usable only if they are related to the macroscopic scale.
- The objective is to reproducibly control the quality, properties, position and density of these nano-objects in order to study and use.

Issues and Context

- Silicon base material
- Why Si is unique?
- Same crystalline structural like diamond
- Indirect GAP: The maximum of the conduction band and the minimum of the valence band does not coincide in wave vector space
- Recent years: significant growth nanostructures: such as nanowires, columns or tubes innovative devices in electronics, energy (PV), optics and biology.
- Nanostructuring of Silicon surface manufacture quantum wells, quantum dots or quantum nanowires additional advantage: confinement of carriers properties

«Small is beautiful»

- Richard feynman's Idea: "There's plenty of room at the bottom", American Physical Society in 1959
- The challenge, even simple, is very important:
- make objects or structures,
- as smallest as possible,
- reproducible manner by controlling their size, their position...

What Application?

- Existing technologies nanostructures: possibility
 * add or remove individual electrons,
 - * turn on and off interactions,
- * tune the electronic state simply by changing the voltage on a gate electrode or an external magnetic field.
- In solar cells application, nanostructured surfaces: increasing photovoltaic conversion rate by the optical confinement

quantum effects

Quantum well:

When the dimensions of the material are smaller than the De Broglie wavelength associated to the electron,

quantum effects

properties of the material associated with the emergence of quantum effects. This wavelength \square_{R} is given by

$$\lambda_{\rm B} = \frac{h}{p} = \frac{h}{\sqrt{2m_{\rm eff}E}}$$

with meff the effective mass of the electron in the semiconductor material, the electron energy E and h Planck's constant.

- To be observed the quantization energy $E > k_B T$ (~ 26 meV at room temperature).
- The associated wavelength is called De Broglie thermal wavelength and given by: $\lambda_{th} = \frac{h}{\sqrt{3m_{eff}k}}$

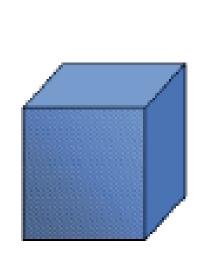
$$\lambda_{th} = \frac{n}{\sqrt{3m_{eff}k_BT}}$$

Why Silicon Surface Nanostructuration? quantum effects

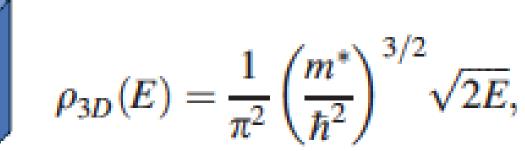
The interest in quantum confined structures is best summarized in the expressions for the density of states (DOS), $\rho(E)$ (number of states per unit volume per unit energy), defined as ∂N

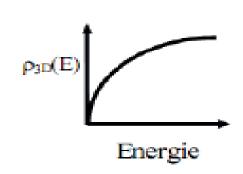
$$\rho(E) = \frac{\partial N}{\partial E}$$

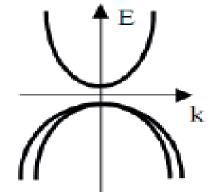
where N is the total number of states per unit volume.



$$N = \frac{k^3}{3p^2}$$

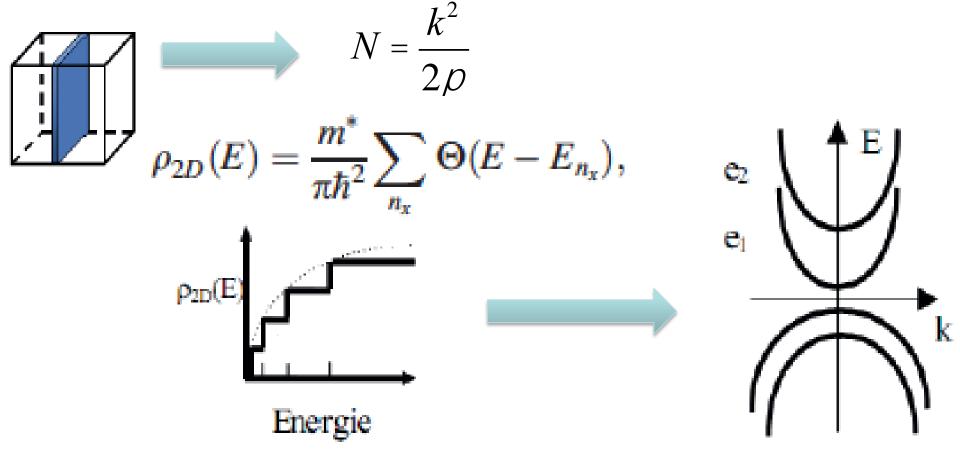






quantum effects

For a 2D system (i.e., two degrees of freedom):

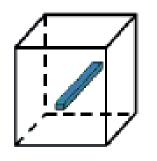


where \Box is the step function and E_{nz} is the energy levels n discretized along z.

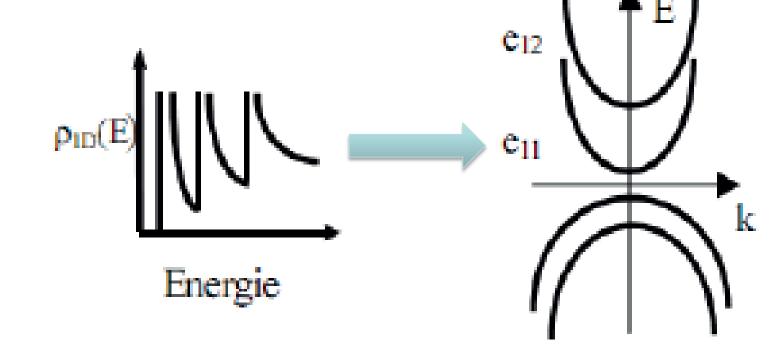
quantum effects

ID For a 1D system:

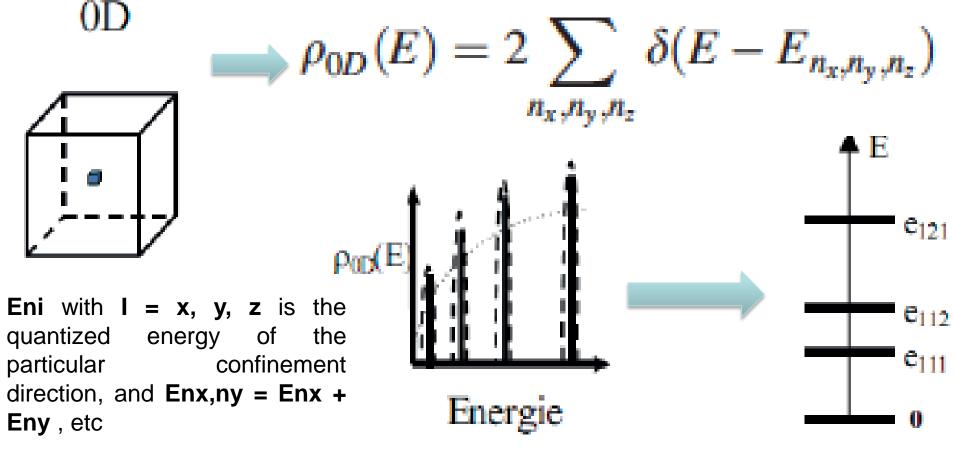
$$N = \frac{2k}{D}$$



$$\rho_{1D}(E) = \frac{1}{\pi\hbar} \sqrt{2m^*} \sum_{n_x,n_y} (E - E_{n_x,n_y})^{-1/2},$$



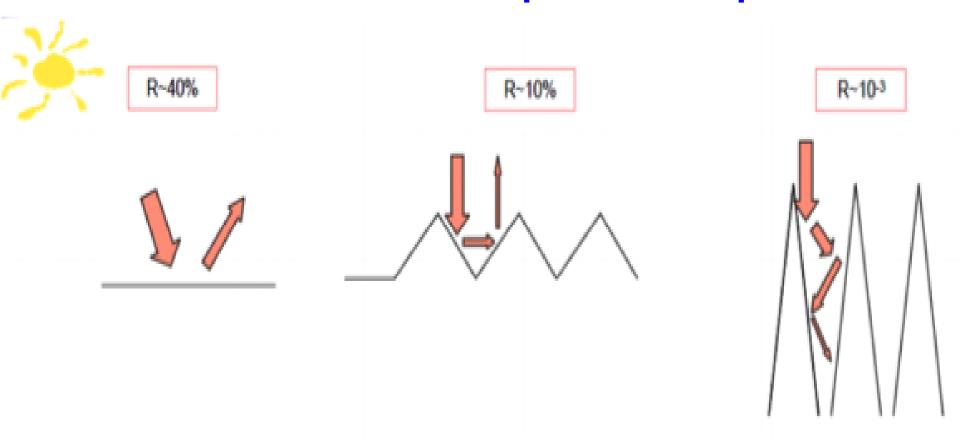
Finally, For a 0D system, there is no **k** -space to be filled and the number density is totally discrete



To first order, in the infinite cubic potential confinement configuration, $t^2 p^2 n^2$

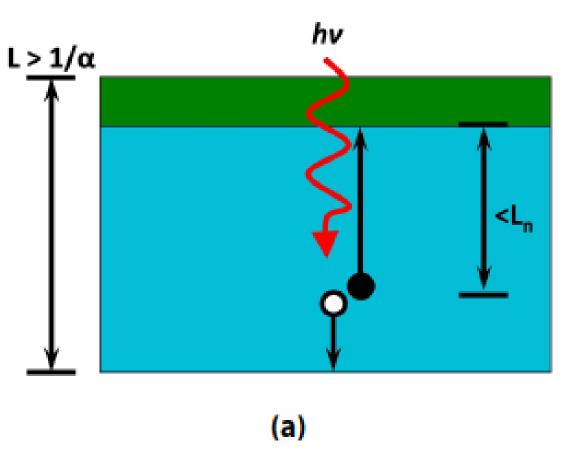
configuration,
$$E_{ni} = \frac{\hbar^2 \rho^2 n_i^2}{2m * D_i^2}$$

Why Silicon Surface Nanostructuration? Effect on Solar Cells Optical Absorption

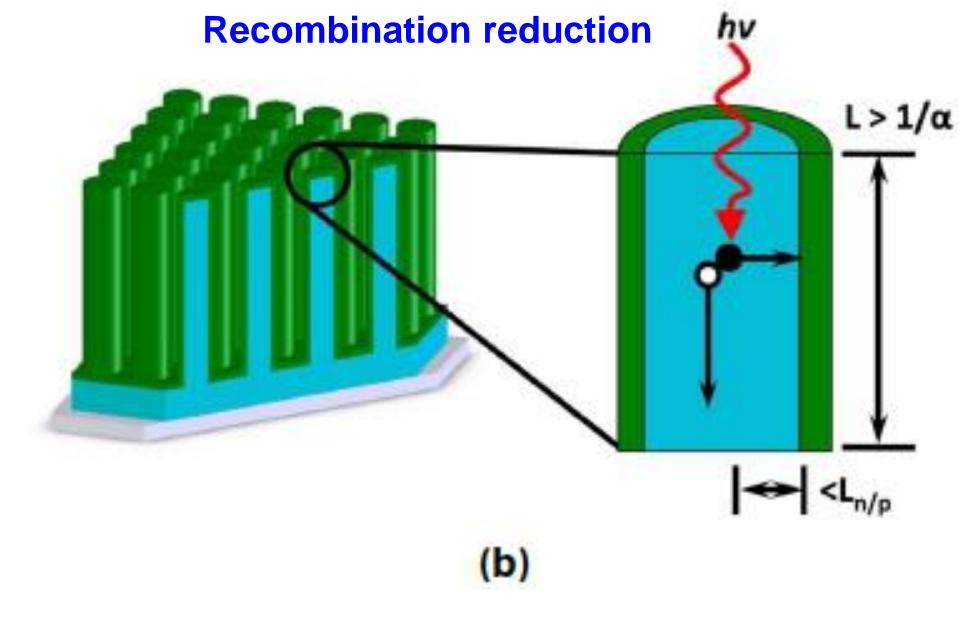


Reduction of reflection depending on the structure of the absorptive surface: increasing optical absorption compared to a thin layer of same thickness

Recombination reduction



According to [1]. Diagram (a) an axial connection and (b) a radial junction.



The stress releasing on the electronic grade silicon for carriers efficient collection.

Silicon Nanowires and Surface Nanostructuration Processes by MACE

- There are a number of techniques to produce nanostructures in Si. But all of these techniques are classified in two principle methods:
- Top Down
- Bottom Up
- Metal-assisted wet-chemical Si etching (MaCE): promising solution high aspect ratio nanostructures, well-defined shapes, and various complexity.
- Metal catalyst: Au, Pt or Ag
- New tentative to use non noble metals: Cu, Zn, Al
- Principle and process used

Silicon Nanowires and Surface Nanostructuration Processes by MACE

Process and Mechanism



Si wafer used characteristics

Fabricant BT Electronics

Synthesised CZ

Type p, Borom doped

Orientation <100>

Résistivité $1-5\Omega.cm$

Polissage 1 face

Thickness 600-650µm



etching

qNO3 + HF solution

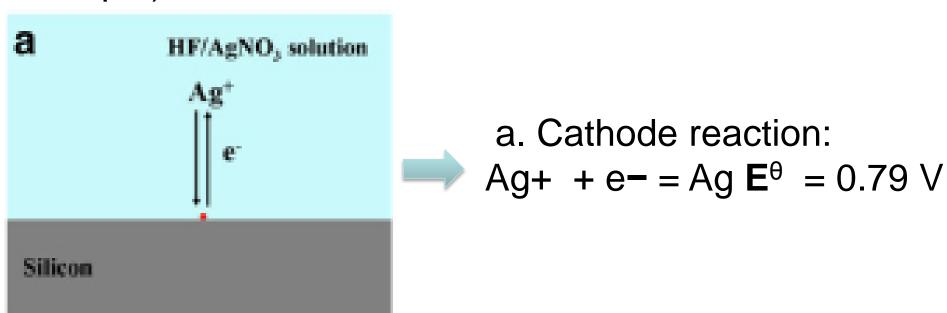
Si p type wafer

Water bath

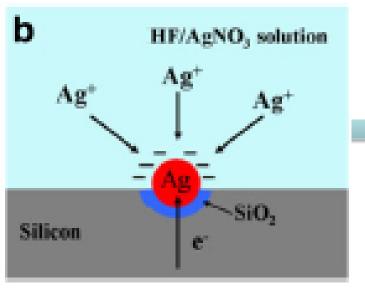
Silicon Nanowires and Surface Nanostructuration Processes by MACE

Process and Mechanism

It can be divided into two processes (taking Ag as an example): 1.

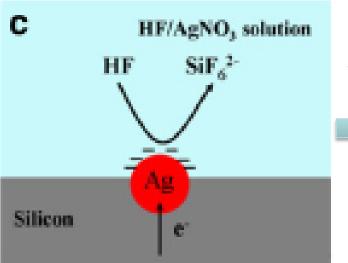


Formation of Ag nucleation



b. Anode reaction: Si + 2H2O = SiO2 + 4H+ + 4e-**E**^θ = 0.91 V

Ag particle growth and Si substrate oxidation.



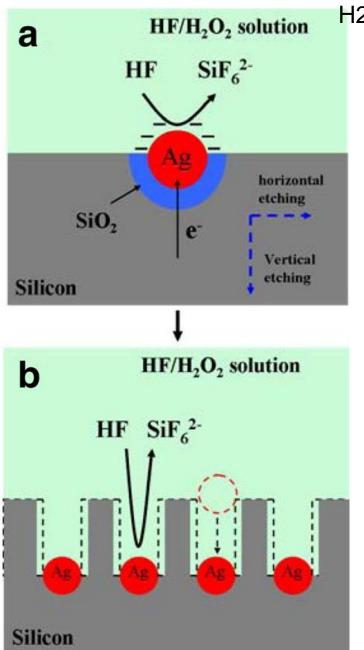
$$SiO2 + 6HF = SiF_6^{2-} + 2H2O + 2H+$$

c. Overall reaction:

$$Si + 6HF + 4Ag^{+} = 4Ag + SiF_{6}^{2-} + 6H+$$

Ag particles trapped in the pits formed by the etching of SiO2 around it by HF

H2O2 concentration effect on NWs morphology



H2O2 = 10 %

a. Cathode reaction:

$$H_2O_2 + 2H^+ \rightarrow 2H_2O + 2h^+$$

 $\mathbf{E}^{\theta} = 1.76 \text{ V}$

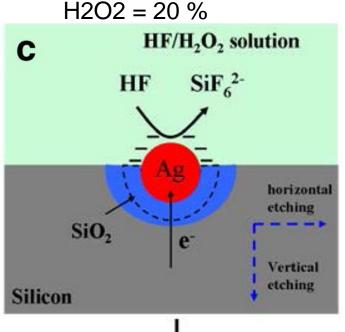
b. Anode reaction:

Si + 6HF +
$$nh^+ \rightarrow H_2SiF_6 + nH^+ + [n/2]H_2$$

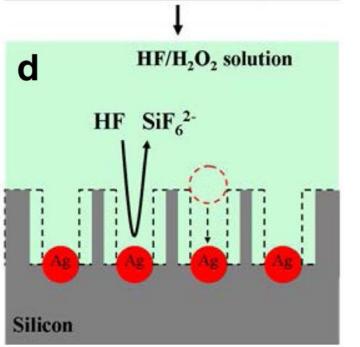
c. Overall reaction:

Si + 6HF + n/2
$$H_2O_2 \rightarrow H_2SiF_6 + nH_2O + [2 - n/2]H_2$$

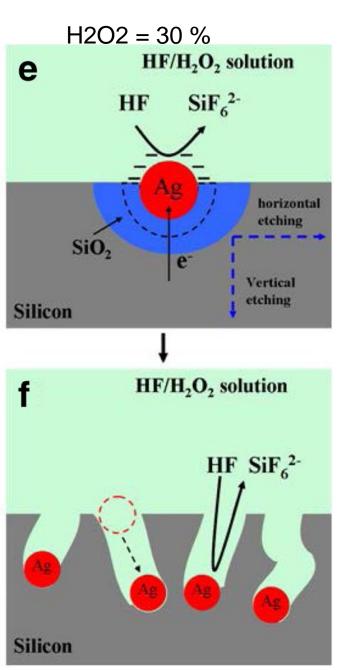
H2O2 concentration effect on NWs morphology



- In the process, AgNO3 plays an important role
- the formation of vertical nanowires is relative to etching limitation around silver nanoparticle
 - etching reaction is along the vertical direction
- H2O2 acts as hole donor and oxidant in the etching process

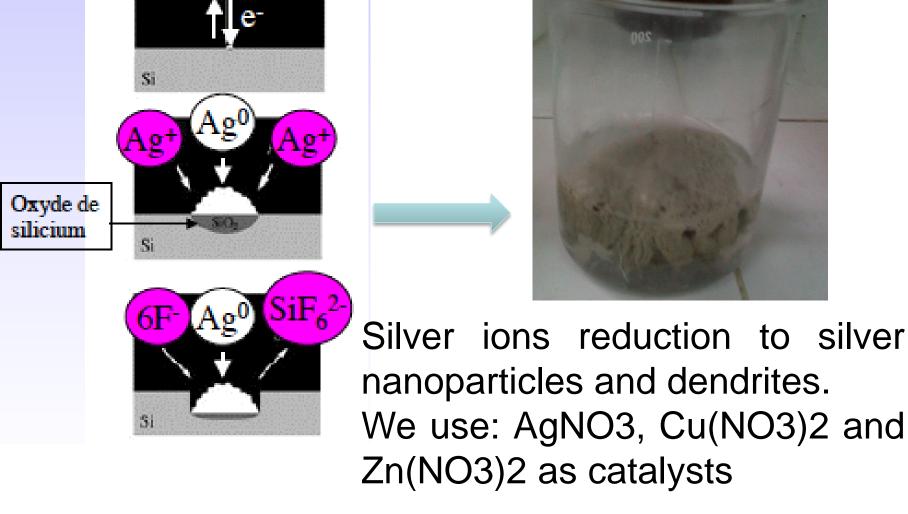


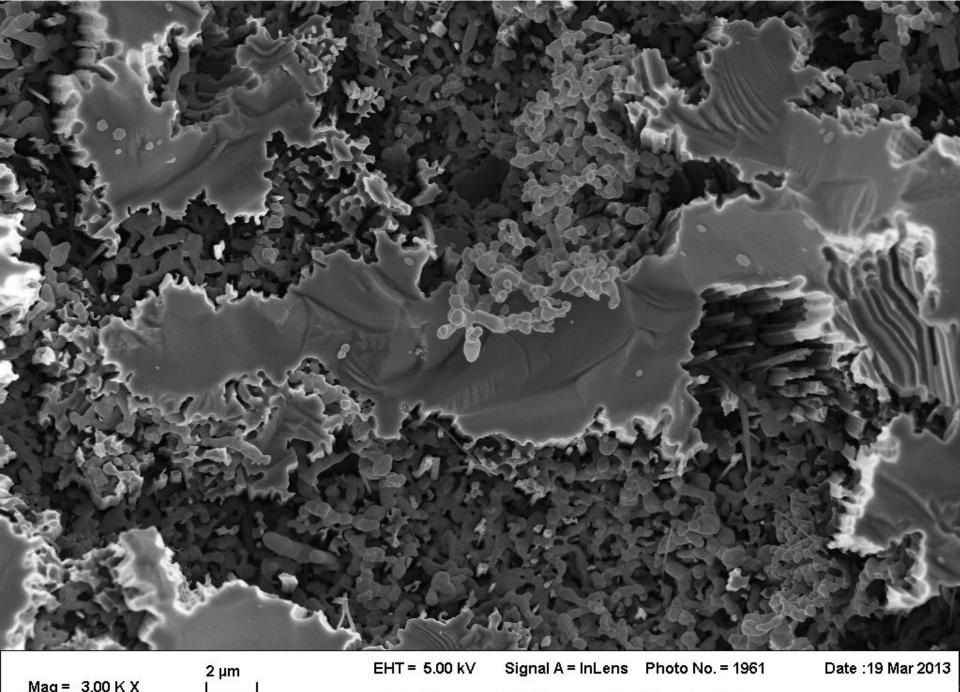
H2O2 concentration effect on NWs morphology



- H2O2 > 30 %, horizontal etching speed increases in a higher degree and overcomes the Ag nanoparticle gravity to shift its position
- Prepared SiNWs do not present an expected morphology of silicon nanowire arrays but a chaotic porous structure on the silicon substrate

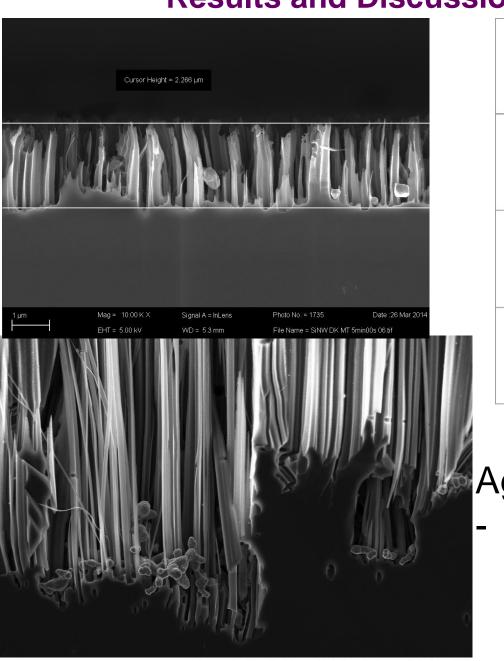
Results and Discussion

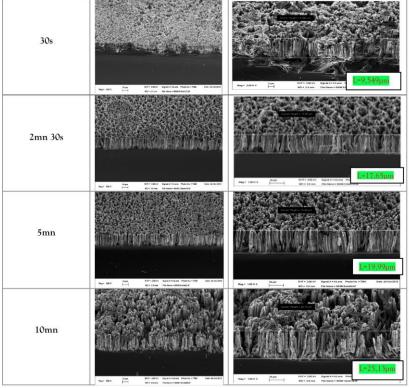




Mag = 3.00 K X WD = 2.6 mm

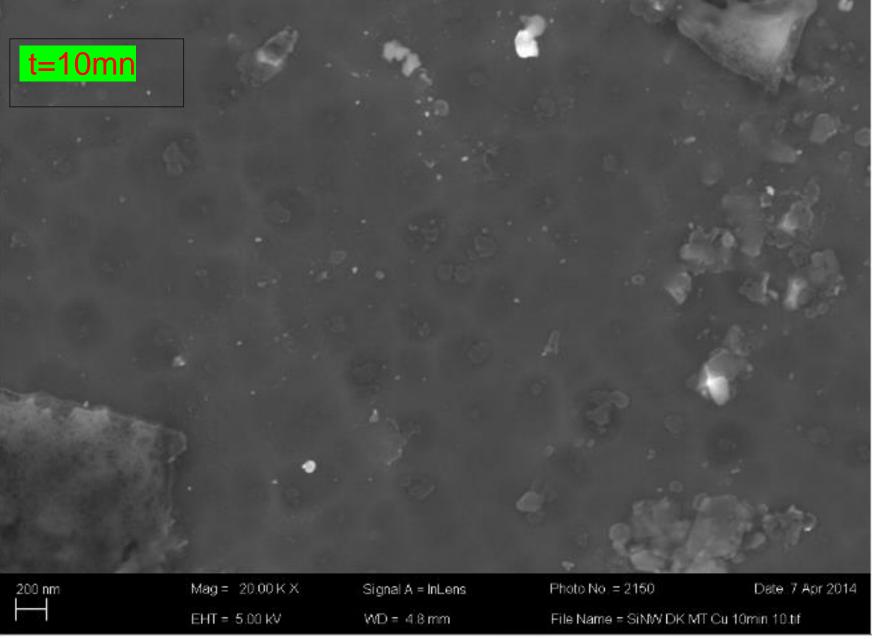
File Name = Si AgNO3 15min 24.tif



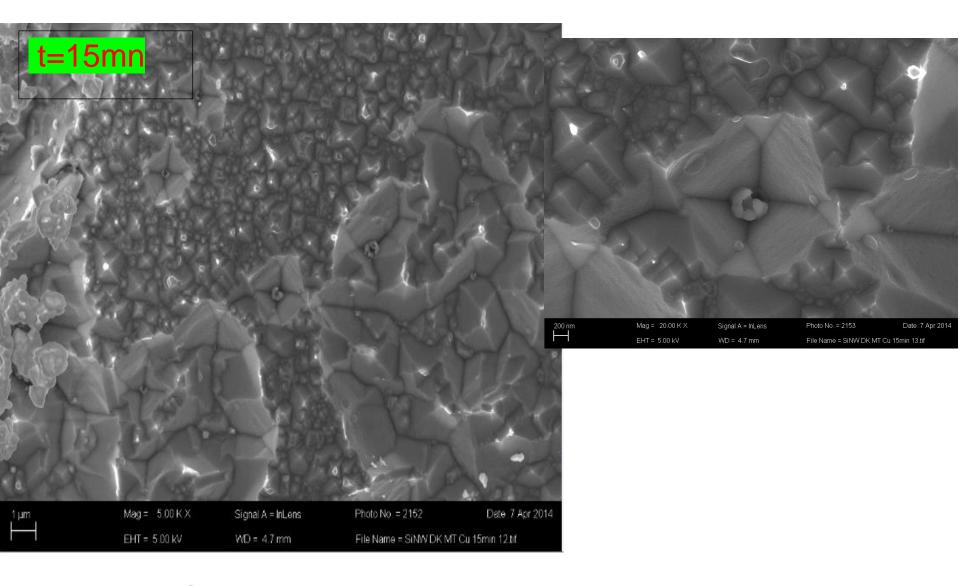


AgNO3 as catalyst:

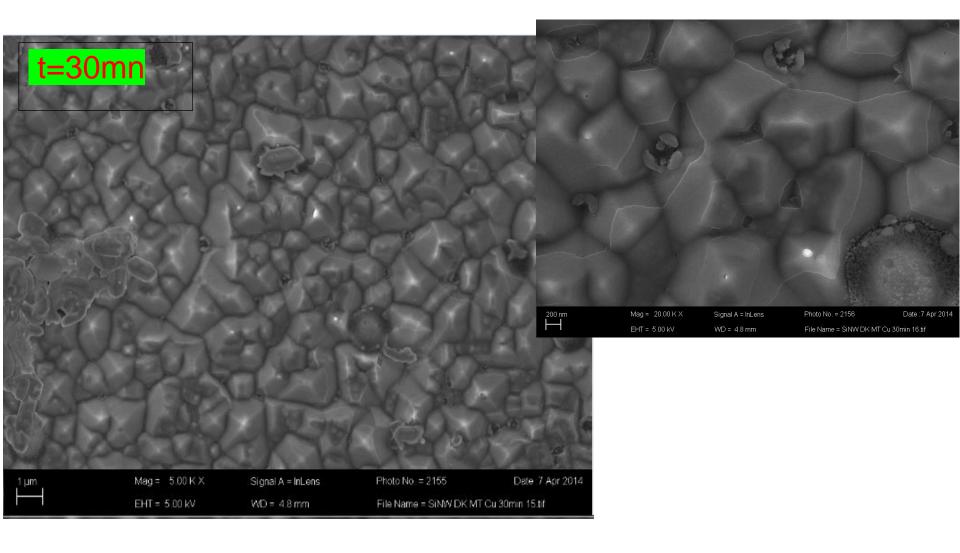
 Nanowires length increases as soon as the etching time



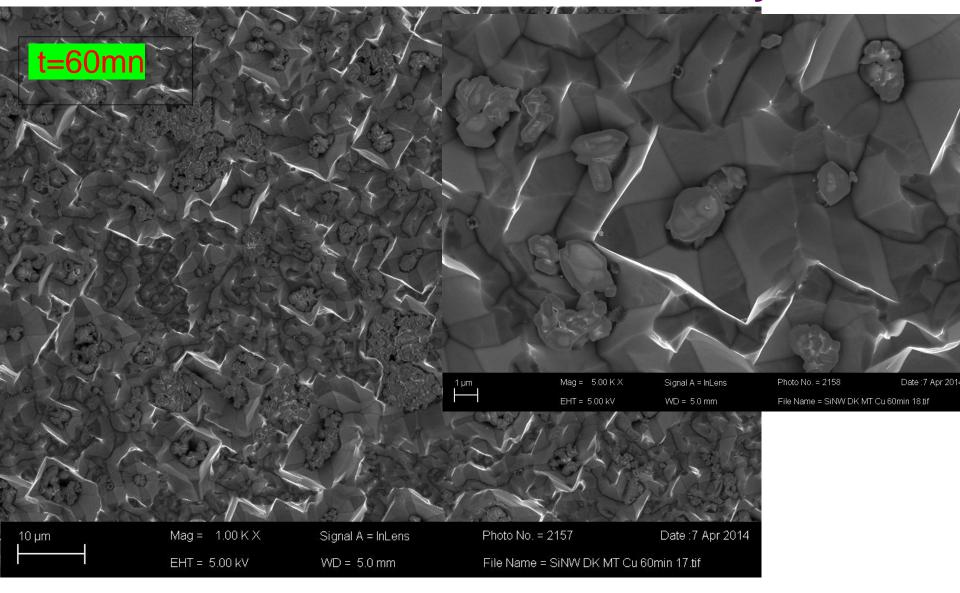
- For etching time below 10 mn, one can observe nuclei points around the surface



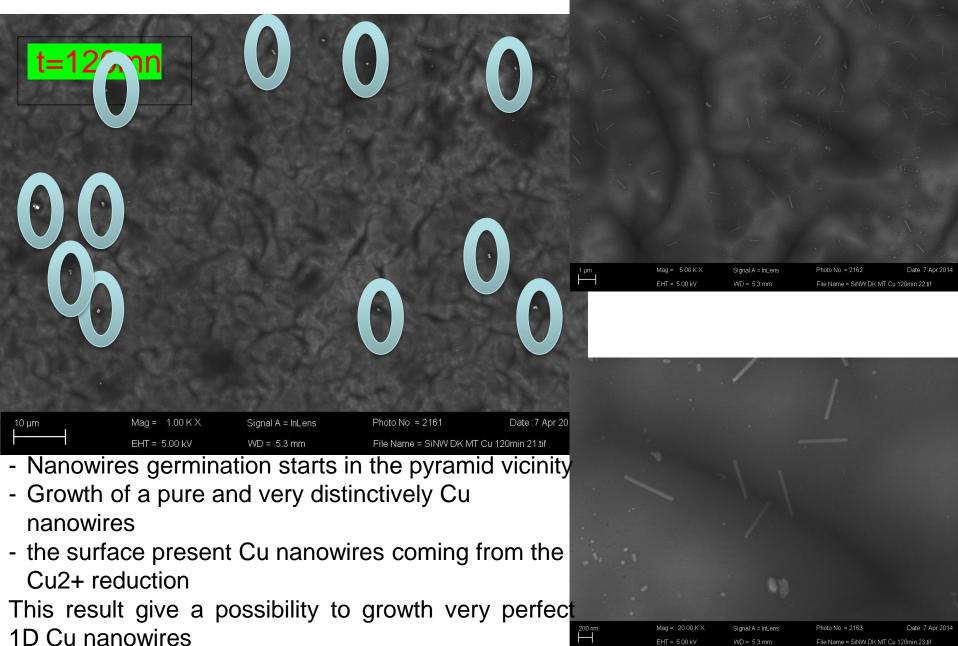
for 15 mn, the Silicon surface present non uniform pyramidal or conical forms

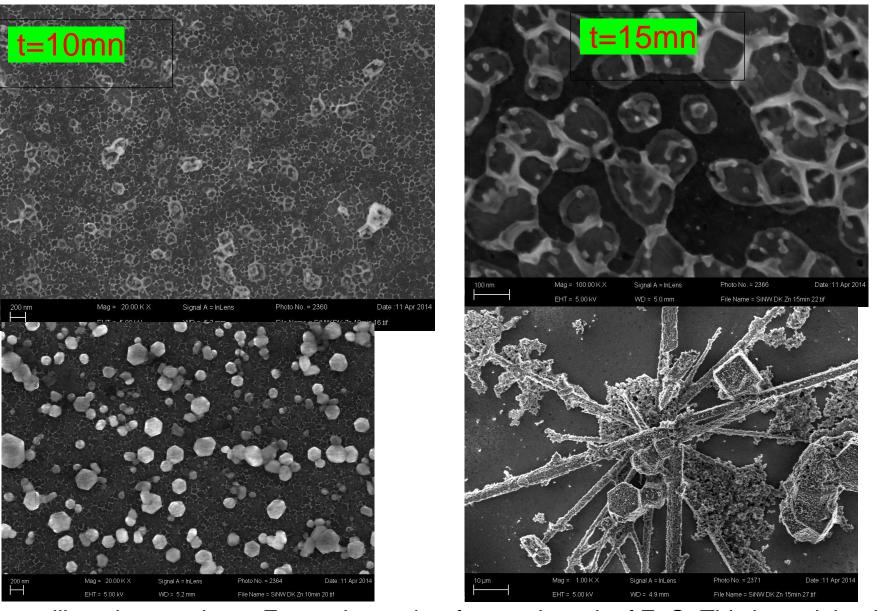


For 30 mn, the surface present uniform pyramidal forms



This structure becomes more symetric pyramidal and reverse pyramidal forms. Presence of the Cu or CuO inside the pyramid coming from the Cu2+ reduction





- unlike other catalysts, Zn catalyst rather form a deposit of ZnO. This is explained by the hexagonal shape that comes from the Wurtzite structure of ZnO.

Conclusion and Perspectives

It is also possible to form nanostructures of spiro-conical nanoholes. This unique form could have potential applications in optoelectronics and biomedicine

Bibliography

- [1]: Kelzenberg., M. D., Nano letters 8, 710 4 (Fev. 2008)
- [2]: Liu et al. Nanoscale Research Letters 2012, 7:663
- [3]: Ksenia Anokhina, phD thesis, Halmstad University, Sweden, 2010
- [4]: D. KOHEN, phD thesis, UNIVERSITÉ DE GRENOBLE, 2006



100 nm

Mag = $60.00 \, \text{K} \, \text{X}$

Signal A = InLens

Photo No. = 727

Date :28 Feb 2014

 $EHT = 5.00 \, kV$

 $WD = 4.9 \, \text{mm}$

File Name = SiNW DK MT 120 min 36.tif